

Form PTO-1449
(Rev. 2-32)U.S. Department of Commerce
Patent & Trademark Office

Atty. Docket No.

Q61326

Serial No.

INFORMATION DISCLOSURE STATEMENT
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Applicant: Kenichiro SUZUKI

Filing Date:

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J0625 U.S. PTO
09/102881
11/01/00

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Sub-Class	Filing Date (if appropriate)
pe ↓	5,043,043	8/91	Howe, et al.	357 216	357 17	
	5,072,288	12/91	MacDonald, et al.	257	420	
	5,428,259	6/95	Suzuki	3101	309	
	5,583,736	12/96	Anderson, et al.	361	234	
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	5,784,189	7/98	Bozler, et al.	357	254	
	5,812,362	9/98	Ravi	361	241	

FOREIGN PATENT DOCUMENTS

Document	Date	Country	Class	Sub-class	Translation Yes/No
8-23685	1/23/96	Japan			Abstract
7-322648	12/8/95	Japan			Abstract
9-163761	6/20/97	Japan			No
6-245551	9/2/94	Japan			No
8-23685	1/23/96	Japan			No
4-340371	11/26/92	Japan			No
7-308080	11/21/95	Japan			No
2-230779	9/13/90	Japan			No
8-180623	7/12/96	Japan			No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

pe ↓	Long-Sheng Fan, et al., "Magnetic Recording Head Positioning at Very High Track Densities Using a Microactuator-Based, Two-State Servo System," <i>IEEE Transactions on Industrial Electronics</i> , Vol. 42, No. 3, June 1995, pp. 222-233.
↓	Youngjoo Yee, et al., "Polysilicon Surface Modification Technique to Reduce Sticking of Microstructures," <i>Transducers '95 - Eurosensors IX</i> , June 1995, pp. 206-209.
↓	A. Benitez, et al., "Bulk silicon microelectromechanical devices fabricated from commercial bonded and etched-back silicon-on-insulator substrates," <i>Sensors and Actuators A</i> , 1995, pp. 99-103.

EXAMINER:

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